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9/9 7/18/03
PATENT
Customer No. 22,852
Attorney Docket No. 04329.2555

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Hiroshi NOMURA) Group Art Unit: 2877
Application No.: 09/816,164) Examiner: G. Stock Jr.
Filed: March 26, 2001)
For: METHOD OF MEASURING)
DISPLACEMENT OF OPTICAL)
AXIS, OPTICAL MICROSCOPE)
AND EVALUATION MARK)

Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT

In reply to the Office Action dated March 28, 2003, the period for reply extending to June 30, 2003 (June 28, 2003 being a Saturday), please amend the application as follows:

IN THE ABSTRACT:

Please amend the Abstract as follows:

A method of measuring the displacement of the optical axis of an optical microscope having an illumination optical system and a projection optical system includes a step of irradiating the evaluation mark having diffraction grating patterns formed on a substrate with illumination light by way of the illumination optical system and observing the evaluation mark by way of the projection optical system to obtain the

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